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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tsuyoshi NISHIZAWA

Group Art Unit: 1722

Application No.: 10/561,957

Examiner: S. MALEKZADEH

Filed: December 22, 2005

Docket No.: 126273

For: METHOD FOR PRODUCING SILICON EPITAXIAL WAFER AND SILICON
EPITAXIAL WAFER

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the April 3, 2007 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.